

JAN 18 2007

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Blaine R. Spady; John D. Heaton; Robert Buchanan; Richard A. Yarussi

Assignee: Nanometrics Incorporated

Title: Metrology/Inspection Positioning System

Serial No.:	09/458,123	Filing Date:	December 8, 1999
Examiner:	Gordon Stock	Group Art Unit:	2877
Docket No.:	NAN035 US	Confirmation No.:	8470

Santa Clara, California
January 18, 2007

Mail Stop RCE
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

This Amendment is filed with a Request for Continued Examination. Please enter the following amendments before taking action on the merits of the above-referenced application.

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